

**AMENDMENTS TO THE CLAIMS**

Please cancel claims 2, 3, 9, 12, 15, 18, 20 and 22, and amend claims 1, 4-8, 10, 11, 13, 14, 16, 17, 19 and 21 as follows:

1. (Currently Amended) ~~An integrated~~ The tool of claim 23 wherein for wet chemical processing of microfeature workpieces, comprising:

~~a frame;~~

~~a mounting module at least partially positioned within the frame, the mounting module having a plurality of positioning elements and attachment elements;~~

~~a workpiece support carried by the mounting module;~~

~~a wet chemical processing chamber carried by the mounting module, the processing chamber having a first interface member engaged with a first one of the positioning elements and a first fastener engaged with one of the attachment elements, the processing chamber further having a vessel with a process location positioned to receive a microfeature workpiece, the processing chamber further having a paddle chamber with an opening at the process location to receive a microfeature workpiece and a plurality of sidewall portions extending downwardly away from the process location, at least one of the sidewall portions including includes a fluid entrance at least proximate to the process location, and at least one of the sidewall portions including includes a fluid exit at least proximate to the process location, and the processing chamber further having a paddle device positioned in the paddle chamber at least proximate to the process location, the paddle device having the at least one paddle is positioned between the fluid entrance and the fluid exit, at least one of the paddle device and the workpiece support being movable relative to the other along a generally linear axis;~~

~~a transport system carried by the mounting module for transporting workpieces within the tool, the transport system having a second interface member engaged with a second one of the positioning elements and a second fastener engaged with one of the attachment elements; and~~

~~wherein the mounting module is configured to maintain relative positions between the first and second positioning elements to be fixed relative to each other such that the transport system does not need to be recalibrated when the processing chamber is replaced with another processing chamber.~~

2. (Cancelled)

3. (Cancelled)

4. (Currently Amended) The tool of claim 4-23 wherein the mounting module includes a deck comprises ing:

a plurality of joists;

~~a rigid first panel attached to one side of the joists and having at least some of (a) the positioning elements and (b) the attachment elements;~~

~~a rigid second panel juxtaposed to the first panel and attached to another side of the joists; and~~

~~wherein the wet chemical processing chamber is attached to the first panel of the deck.~~

5. (Currently Amended) The tool of claim 4-23 wherein the mounting module further comprises:

~~a processing deck includes a comprising an upper panel, a lower panel under the upper panel and braces attached between the upper and lower panels, the upper panel having (a) the first positioning element and (b) at least some of the attachment elements; and wherein the mounting module further includes a platform having the second positioning element and being fixedly disposed in the tool relative to the processing deck.~~

6. (Currently Amended) The tool of claim 4-23 wherein the mounting module ~~includes~~ comprises a deck for carrying the wet chemical processing chamber, a platform for carrying the transport system, and ~~adjustable footings for adjustably attaching the mounting module to the frame, and wherein:~~

the deck ~~includes~~ comprises a plurality of joists, a rigid first panel attached to one side of the joists and having a first set of the positioning elements and a first set of the attachment elements, and a rigid second panel juxtaposed to the first panel and attached to another side of the joists;

the platform ~~comprises~~ includes a second set of positioning elements and a second set of attachment elements;

the wet chemical processing station is carried by the deck and includes a plurality of first interface members and a plurality of first fasteners, and ~~with~~ the first interface members being engaged with corresponding positioning elements of the first set of positioning elements, and with the first fasteners being engaged with corresponding attachment elements of the first set of attachment elements; and wherein

the transport system is carried by the platform and includes a plurality of second interface members and a plurality of second fasteners, and with the second interface members being engaged with corresponding positioning elements of the second set of positioning elements, and with the second fasteners being engaged with corresponding attachment elements of the second set of attachment elements.

7. (Currently Amended) The tool of claim 4-23 wherein:

the wet chemical processing chamber is a first electrochemical deposition chamber comprising a first vessel, a first workpiece support disposed relative to the first vessel to hold a workpiece in a processing solution, a first cathodic electrode disposed in one of the first vessel or the first workpiece support,

and a first anodic electrode disposed in the other of the first vessel or the first workpiece support; and wherein

the tool further comprises a second electrochemical deposition chamber comprising a second vessel, a second workpiece support disposed relative to the second vessel to hold a workpiece in a processing solution, a second cathodic electrode disposed in one of the second vessel or the second workpiece support, and a second anodic electrode disposed in the other of the second vessel or the second workpiece support.

8. (Currently Amended) The tool of claim 423 wherein:

the wet chemical processing chamber is a first electrochemical deposition chamber comprising a first vessel, a first workpiece support disposed relative to the first vessel to hold a workpiece in a processing solution, a first cathodic electrode disposed in one of the first vessel or the first workpiece support, and a first anodic electrode disposed in the other of the first vessel or the first workpiece support; and wherein

the tool further includes a second wet chemical processing chamber comprising a cleaning chamber having a fluid delivery system that directs a cleaning fluid onto a workpiece.

9. (Cancelled)

10. (Currently Amended) The tool of claim 423 wherein the mounting module is configured to maintain relative positions between the first and second positioning elements to within approximately 0.005 to 0.015 inch.

11. (Currently Amended) The tool of claim 423, further comprising:  
a workpiece support carried by the mounting module; and

- a controller operatively coupled to the at least one of the paddle device and the workpiece support, the controller being configured to move the at least one of the at least one paddle device and the workpiece support relative to the other in a reciprocal manner along a generally linear axis, with a stroke of the relative motion changing between at least two successive reciprocations.

12. (Cancelled)

13. (Currently Amended) The tool of claim 4-23 wherein the paddle device includes a plurality of paddles having spaced apart paddle surfaces and being reciprocally movable relative to the process location along a generally linear motion axis.

14. (Currently Amended) The tool of claim 423, further comprising a magnet positioned proximate to the process location to orient material deposited on a microfeature workpiece at the process location.

15. (Cancelled)

16. (Currently Amended) The tool of claim 4-23 wherein the at least one paddle has a first surface and a second surface facing opposite from the first surface, the first and second surfaces being canted outwardly and downwardly away from an axis positioned between the surfaces and normal to the process location.

17. (Currently Amended) The tool of claim 4-23, further comprising a workpiece support positioned to carry a workpiece at the process location, and wherein the at least one paddle is at least partially transmissive to the processing fluid to allow the processing fluid to pass through the at least one paddle as a result of relative motion between the at least one paddle and the workpiece support.

18. (Cancelled)

19. (Currently Amended) The tool of claim 4-23 wherein the process location includes a portion of a generally planar process plane, and wherein the tool further comprises an electrode support positioned to carry a thieving electrode remote from the process plane.

20. (Cancelled)

21. (Currently Amended) The tool of claim 1, further comprising a workpiece support positioned to carry a workpiece at the process location, and wherein the process location includes a process plane, and wherein the workpiece support is positioned to rotate a microfeature workpiece at the process plane about an axis generally normal to the process plane.

22. (Cancelled)

23. (Previously Presented) An integrated tool for wet chemical processing of microfeature workpieces, comprising:

- a mounting module comprising a deck having a rigid outer member with a plurality of positioning elements and a plurality of attachment elements, a rigid interior member juxtaposed to the outer member, and bracing between the outer member and the interior member, wherein the outer member, the bracing and the interior member are fixed together to be dimensionally stable;

- a wet chemical processing station attached to the deck, the wet chemical processing station having a first interface member engaged with at least a first one of the positioning elements and a fastener engaged with an attachment element, the wet chemical processing station further including a vessel having a process location positioned to receive a microfeature

- workpiece, the processing station further including a paddle chamber having an opening at the process location to receive a microfeature workpiece, the paddle chamber further having a plurality of sidewall portions extending downwardly away from the process location, and a base portion having a first surface facing toward the process location and a second surface facing opposite from the first surface, with the second surface inclined to have a higher elevation toward a perimeter of the process location than toward a center of the process location, the processing station further having a paddle device positioned in the paddle chamber, the paddle device having at least one paddle and being movable relative to the process location; and
- a workpiece transport system attached to the mounting module and having a second interface member engaged with at least a second one of the positioning elements, wherein the first and second positioning elements are fixed relative to each other.

24. (Original) The tool of claim 23 wherein the outer member is superimposed over the interior member, and the deck further comprises a plurality of bolts clamping the outer member to one side of the bracing the clamping the interior member to another side of the bracing.

25. (Original) The tool of claim 23 wherein the bracing comprises horizontal joists, the outer member comprises a rigid top panel attached to a top side of the joists, the interior member comprises a bottom panel superimposed under the top panel and attached to an underside of the joists, and the deck further comprises a plurality of bolts extending through the bracing to clamp the top panel and the bottom panel to the joists.

26. (Original) The tool of claim 23 wherein the top panel, the joists, and the bottom panel are configured to maintain relative positions between the positioning elements across the top panel to within 0.025 inch.

27. (Previously Presented) The tool of claim 23 wherein the base portion is spaced apart from the process location by a first distance along a first axis generally normal to the process location and wherein the at least one paddle extends for a second distance generally parallel to the first axis, the second distance being at least 70% of the first distance.

28. (Original) The tool of claim 23, further comprising:

- a magnet positioned at least proximate to the process location, the magnet being positioned to impose a magnetic field at the process location to orient material deposited on a microfeature workpiece; and
- an electrode support positioned to carry at least one electrode in fluid communication with the process location, the electrode support being movable relative to the vessel between a process position and a removed position along a motion path that does not pass through the process location.

29. (Original) The tool of claim 23 wherein the paddle device includes a first paddle and a second paddle, with at least a portion of the second paddle being spaced apart from the first paddle, the first paddle having a first shape and size and the second paddle having a second shape and size, with the first shape being different than the second shape, or the first size being different than the second size, or both.

30. (Original) The tool of claim 23, further comprising an electrode support positioned to be in fluid communication with the process location, the electrode support having a plurality of electrode chambers at least partially separated from each other by dielectric barriers, with gaps between the dielectric barriers forming a corresponding plurality of virtual electrode locations spaced apart from the process location.



31. (Original) The tool of claim 23, further comprising:  
an electrode support configured to carry at least one electrode, the electrode support being in fluid communication with the process location; and  
an electric field control element positioned along a flow path between the electrode support and the process location, the electric field control element being configured control an electrical current density in the processing fluid at the process location to have a first value at a first circumferential site of the process location and a second value different than the first value at a second circumferential site of the process location.

32-40. (Cancelled)